



PATENT  
Dkt. No.: 29273/559

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS: Yuko IWABUCHI, et al.  
SERIAL NO. : 10/083,481  
FILED : February 27, 2002  
FOR : METHOD AND AN APPARATUS OF AN INSPECTION SYSTEM  
USING AN ELECTRON BEAM  
GROUP ART : 2881  
EXAMINER : Jack I. Berman

ASSISTANT COMMISSIONER FOR  
PATENTS AND TRADEMARKS  
Washington D.C. 20231

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**RESPONSE TO OFFICE ACTION**

Sir:

In response to the Office Action dated July 28, 2003, the due date being extended by the attached Extension of Time, please amend the above-identified application as follows:

**IN THE CLAIMS:**

1. (Currently Amended) An inspection method for detecting a defect of a specimen by using an electron beam, said method comprising the steps of:  
determining a beam current of the electron beam to be at least 100nA based on a signal to noise ratio of an image of the defect and an inspection time;  
deflecting said electron beam set at least 100nA beam current by taking a crossover as a fulcrum;  
applying a retarding voltage for decelerating the electron beam to said specimen; and  
changing the magnitude of said retarding voltage based on the nature of said specimen.

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